

ABSTRACT OF THE DISCLOSURE

A silicon tower for removably supporting a plurality of silicon wafers during thermal processing. A tower includes plural silicon legs secured on their ends to two bases. A plurality of slots are cut in the legs allowing slidable insertion of the wafers and support for them. Preferably, the teeth incline upwardly at 1-3° and have horizontal support areas polished on their ends. Preferably, the legs are machined from virgin polysilicon formed by chemical vapor deposition from silane. The bases may be either virgin poly or monocrystalline silicon and be either integral or composed of multiple parts. Virgin polysilicon is preferably annealed to above 1025°C before machining.

5 Silicon parts may be joined by applying a spin-on glass between the parts and annealing the assembly.

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